



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Vlad J. Novotny and Parvinder Dhillon

Assignee: Active Optical Networks, Inc.

Title: "MICRO-ELECTRO-MECHANICAL SWITCHING SYSTEM"

Serial No.: 10/035,829 Filed: 10/18/2001

Examiner: Stahl, Michael J. Tel: 571-272-2360

Docket No.: AO-666 Art Unit: 2874  
[AONIP001C1]

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INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, §1.97 and §1.98, Applicants bring the 16 documents listed on the enclosed forms PTO-1449 to the Examiner's attention in the above-captioned application. Citation of the listed documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant application;
2. a representation that a search has been made; or
3. an admission that the information cited is, or is considered to be, material to patentability as defined in §1.56(b).

I hereby certify that this correspondence is being deposited with the United States Postal Service via First Class Mail and is addressed to: Mail Stop: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

4.19.64  
Date

Laurie Moreno

Respectfully submitted,

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U.S. Department of Commerce, Patent and Trademark Office		Serial No.: 10/035,829
		Filing Date: 10/18/2001
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT		First Named Inventor: Vlad J. Novotny
"Micro-Electro-Mechanical Switching System"		Group Art Unit: 2874
		Examiner Name: Stahl, Michael J.
		Attorney Docket No.: AO-666 AONIP001C1

#### U.S. Patent / Patent Publication Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date, If Appropriate
	A	6,028,689	02/22/00	Michalicek et al.	359	224	
	B	6,253,001 B1	06/26/01	Hoen	385	17	
	C	6,283,601 B1	09/04/01	Hagelin et al.	359	871	
	D	6,301,403 B1	10/09/01	Heanue et al.	385	18	
	E	US 2002/0171327 A1	11/21/02	Miller et al.	310	309	

#### OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

	F	ELWENSPOEK, M. et al., "Silicon Micromachining." 1998 - Cambridge University Press. Cover page, pages 102-111, pages 160-161 and page 282.
	G	MALUF, NADIM, "An Introduction to Microelectromechanical Systems Engineering." 2000. Cover page, pages 6464-73 and pages 186-189.
	H	RAI-CHOUDHURY, P., "Handbook of Microlithography, Micromachining, and Microfabrication." 1997 - SPIE Optical Engineering Press. Pages 110-116 and pages 120-122.
	I	CONANT, ROBERT A. et al., "A Flat High-Frequency Scanning Micromirror." 2000 - Solid-State Sensor & Actuator Workshop, Hilton Head, SC.
	J	BEZUK, STEVE, PH.D., "Flip Chip Challenges." 02/00 - HD Magazine. 6 pages.
	K	CHEN, YIJIAN, "Control and Shape Design of an Electrically-Damped Comb Drive for Digital Switches." 2000 - MOEMS and Miniaturized Systems. Proceedings of SPIE Vol. 4178. Pages 387-394.
	L	DAWSON, J.M. et al., "MEMS Feedback Control Using Through-Wafer Optical Device Monitoring." September 2000 - Proc. Of SPIE Vol. 4178, MOEMS and Miniaturized Systems.

Examiner	Date Considered
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\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



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## U.S. Patent / Patent Publication Documents

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	M						
	N						
	O						
	P						
	Q						

## OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

R	LEE, SANGWOO, et al., "The Surface/Bulk Micromachining (SBM) Process: A New Method for Fabricating Released MEMS in Single Crystal Silicon." December 1999. Journal of Microelectromechanical Systems, Vol. 8, No. 4. Pages 409-416.
S	MILANOVIC, VELJKO, "Optical MEMS for Optical Communications - Trends and Developments." 12/01. Adriatic Research Institute. Pages 2-6.
T	NEE, JOCELYN T. et al., "Lightwave, Optically Flat Micromirrors for Fast Beam Steering." Presented at IEEE/LEOS Optical MEMS August 2000 Conference in Kauai, Hawaii. 2 pages.
U	TIEN, NORMAN C. et al., "MEMS Actuators for Silicon Micro-Optical Elements." 2000 - Proceedings of SPIE Vol. 4178. Pages 256-267.
V	
W	
X	

Examiner Date Considered

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